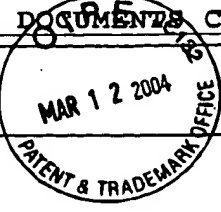














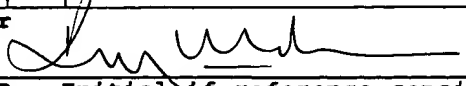


FORM PTO-1449				Atty. Docket No. XA-9387		Appln. No. 09/714,183	
<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>				Applicant Hitoshi TAKEUCHI			
				Filing Date November 17, 2000		Group 2877	
				U.S. PATENT DOCUMENTS			
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA	4,141,652	2/27/79	Feinleib	356	121	
	AB	4,326,800	4/27/82	Fitts	356	152	
	AC	4,518,854	5/21/85	Hutchin	250	201	
	AD	4,666,298	5/19/87	Protz	356	121	
	AE	5,362,956	11/8/94	Anafi et al.	250	201.9	
	AF	5,760,879	6/2/98	Shinonaga et al.	355	55	
	AG	5,898,501	4/27/99	Suzuki et al.	356	359	
	AH	5,978,085	11/2/99	Smith et al.	356	354	
	AI	6,278,514	8/21/01	Ohsaki	355	55	
	AJ	6,360,012	3/19/02	Kreuzer	382	211	
	AK	5,828,455	10/27/98	Smith et al.	356	354	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AL	WO99/66308	12/23/99	WIPO			
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER (including author, title, date, pertinent pages, etc.)							
	AR	Freitag et al., "Wavefront analysis of photolithographic lenses," JR, 1/1991, pp. VIII-XII.					
	AS	Noguchi et al. "Shack-Hartmann Wave-Front Analyzer to Measure F/5 Mirrors," Active Optic Experiments. I., 1989, Publ. Natl. Astron. Obs. Japan, Vol. 1, 49-55.					
Examiner 				Date Considered 06/17/2004			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							